

# Process Enabled Custom Component Design Flow for Photonic Integrated Circuits

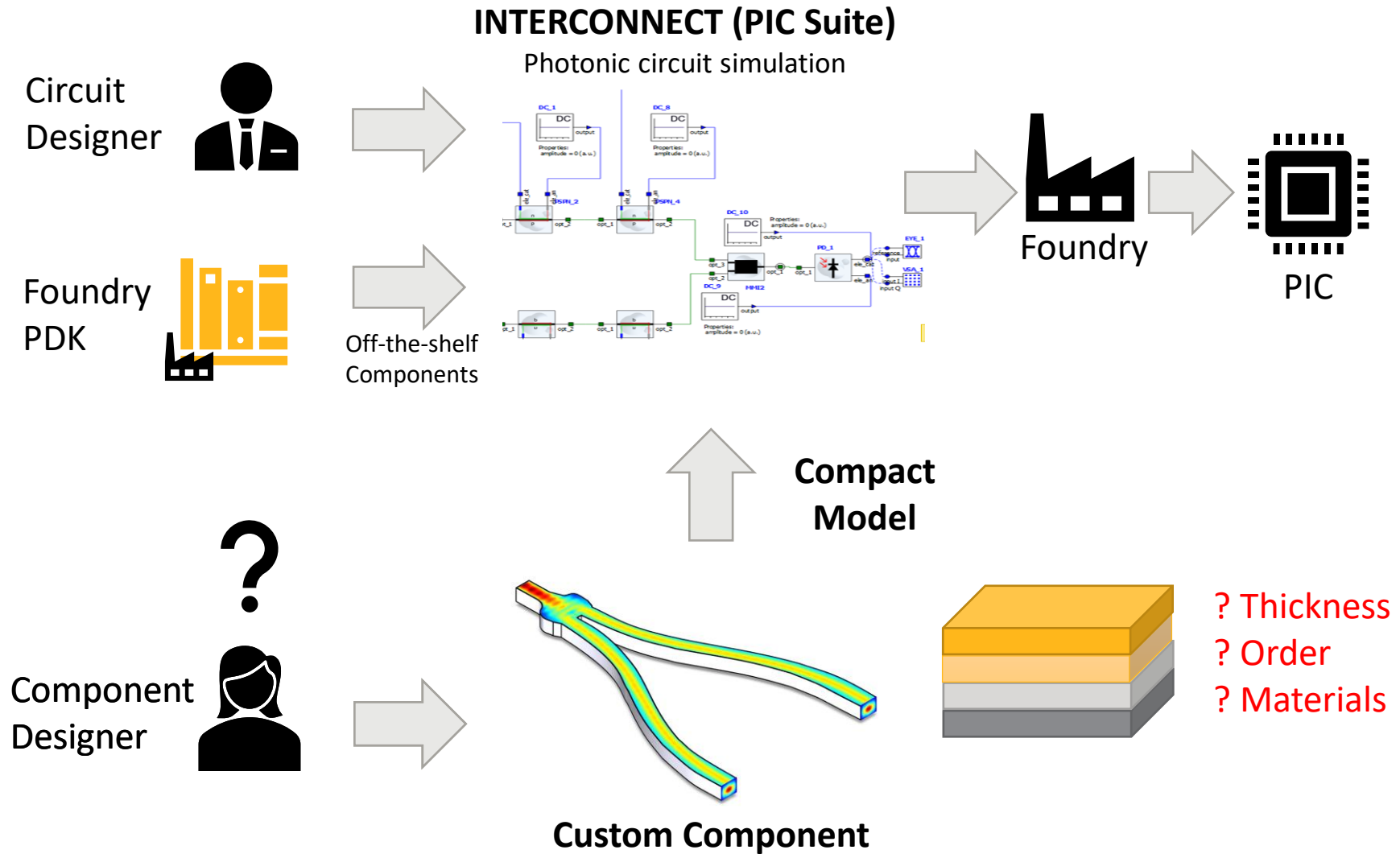
Ahsan Alam, Ansys (Lumerical)



# Outline

- Motivation
- Enabling a complete photonic design ecosystem
- Custom component design with Layer builder
- Support for active components
- See it in action
- Support for process variations
- Q&A

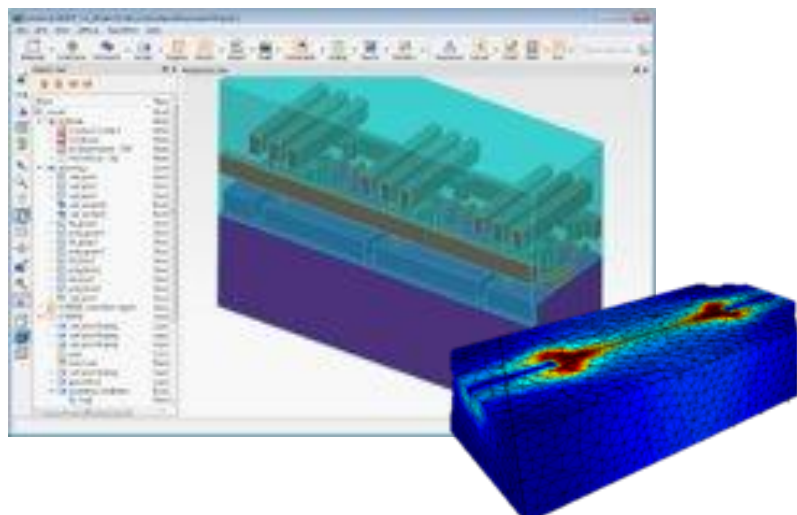
# Foundry Compatible Custom Component Design



<https://www.ansys.com/blog/design-foundry-compatible-photonic-components>

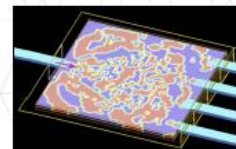
# A Comprehensive Suite of Leading Photonic Design Tools

## PHOTONIC MULTIPHYSICS SIMULATION



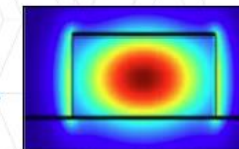
### FDTD

3D Electromagnetic Solver



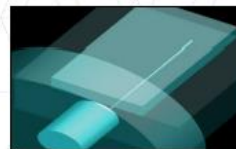
### FDE

Finite-difference Eigenmode Solver



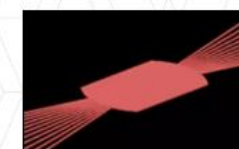
### EME

Finite-Difference Eigenmode Expansion Solver



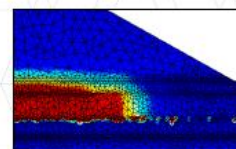
### varFDTD

2.5D variational FDTD Solver



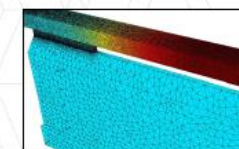
### CHARGE

3D Charge Transport Simulator



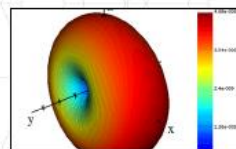
### HEAT

3D Heat Transport Solver



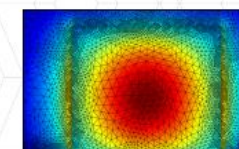
### DGTD

3D Electromagnetic Solver



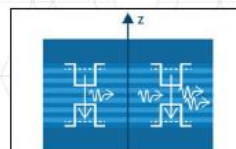
### FEEM

Waveguide Solver



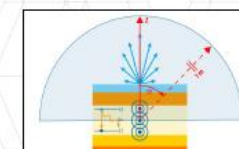
### MQW

Quantum Well Gain Solver



### STACK

Optical Multilayer Solver

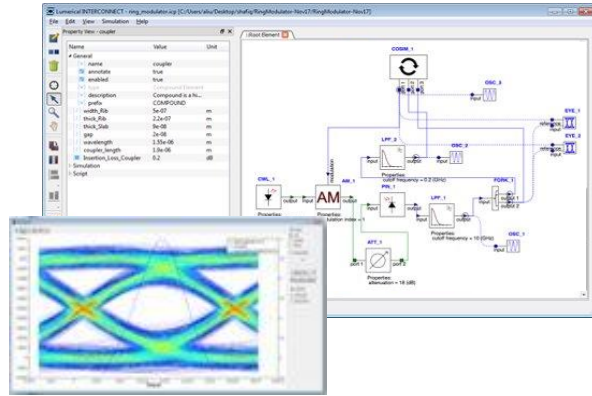




# A Comprehensive Suite of Leading Photonic Design Tools

## PHOTONIC INTEGRATED CIRCUIT SIMULATION

### INTERCONNECT

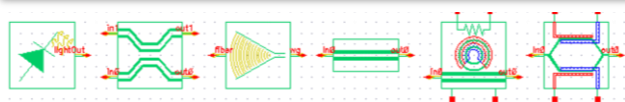


### CML Compiler

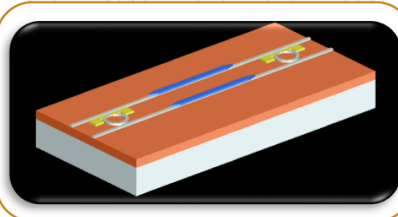
#### INTERCONNECT compact models



#### Photonic Verilog-A models (Virtuoso)



Laser



Electro-Optic Modulator

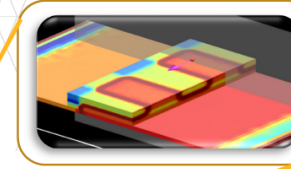
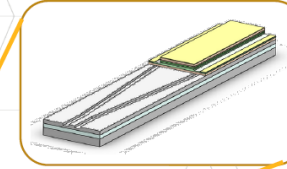
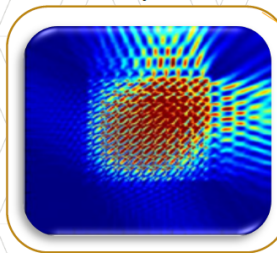


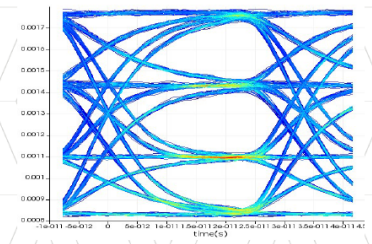
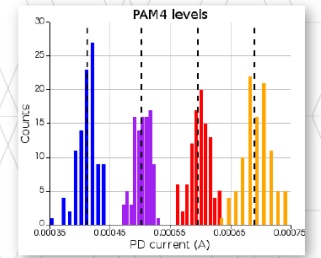
Photo-detector



Grating Coupler



Communication Link  
Characterization & Yield Analysis



Open Ecosystem



Automation



Optimization

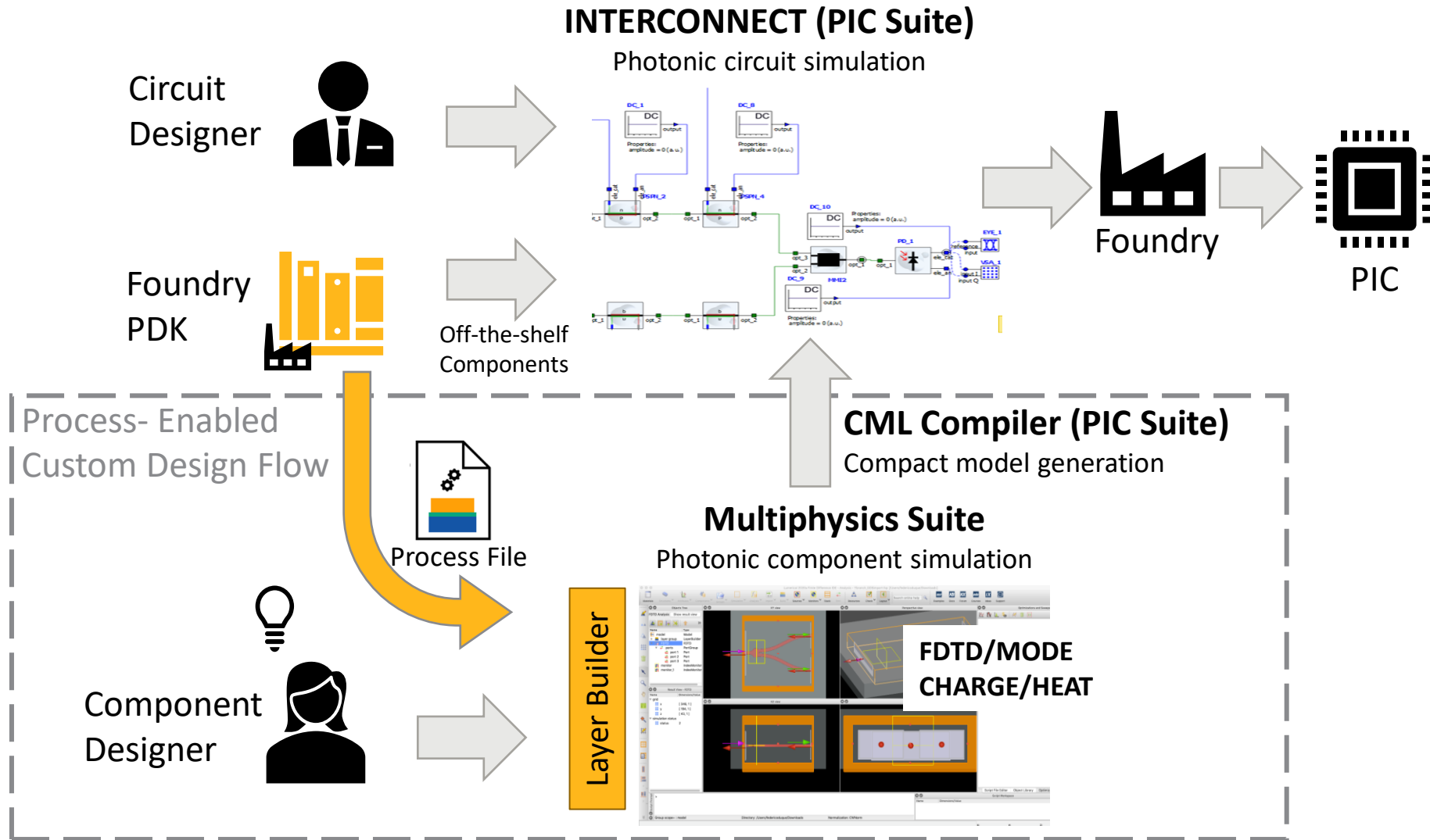


Cloud & HPC  
Acceleration



Foundry PDK  
Enablement

# Process-enabled Custom Component Design



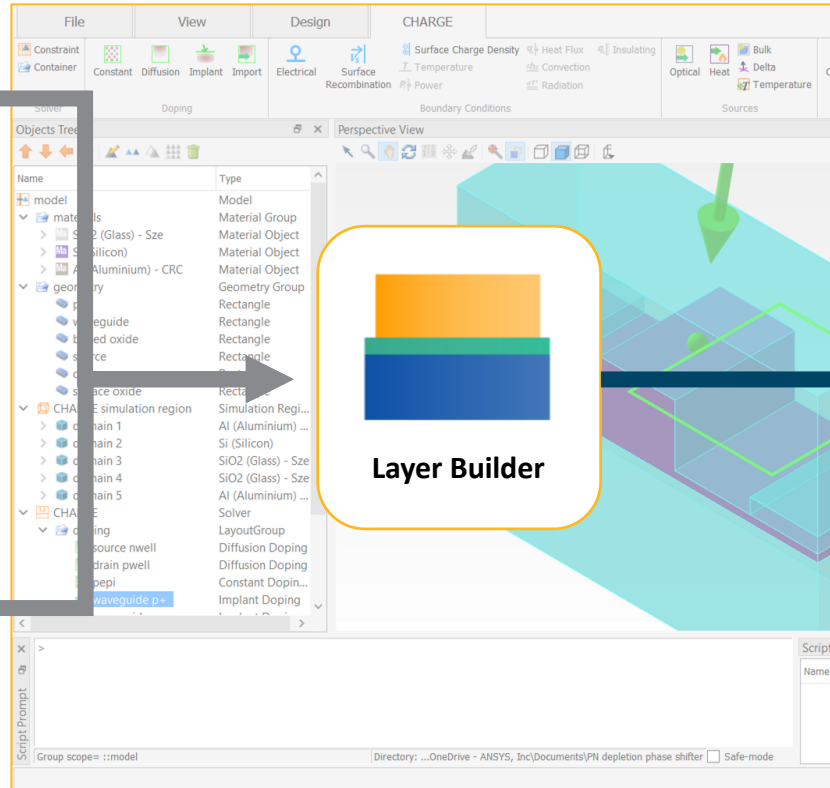
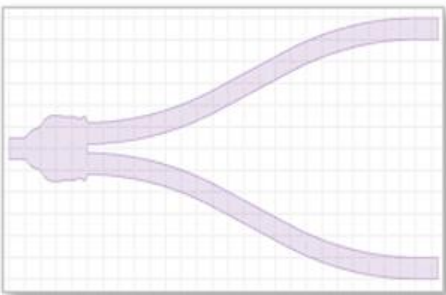
<https://www.ansys.com/blog/design-foundry-compatible-photonic-components>

# How Does Layer Builder Work?

Process file with  
layer definition



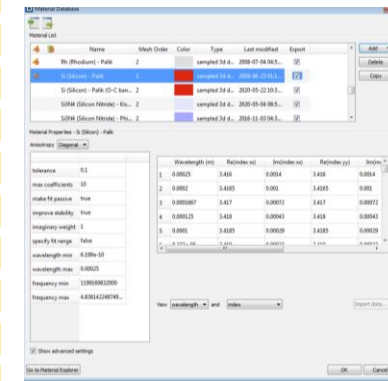
GDS-II file with geometry  
definition



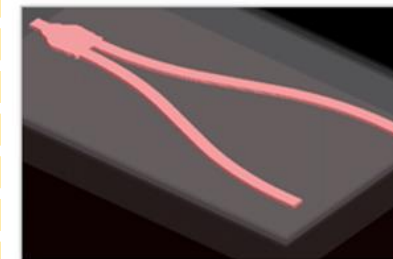
Layer Builder

Simulation settings

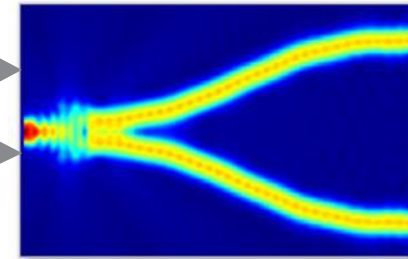
Optical material data



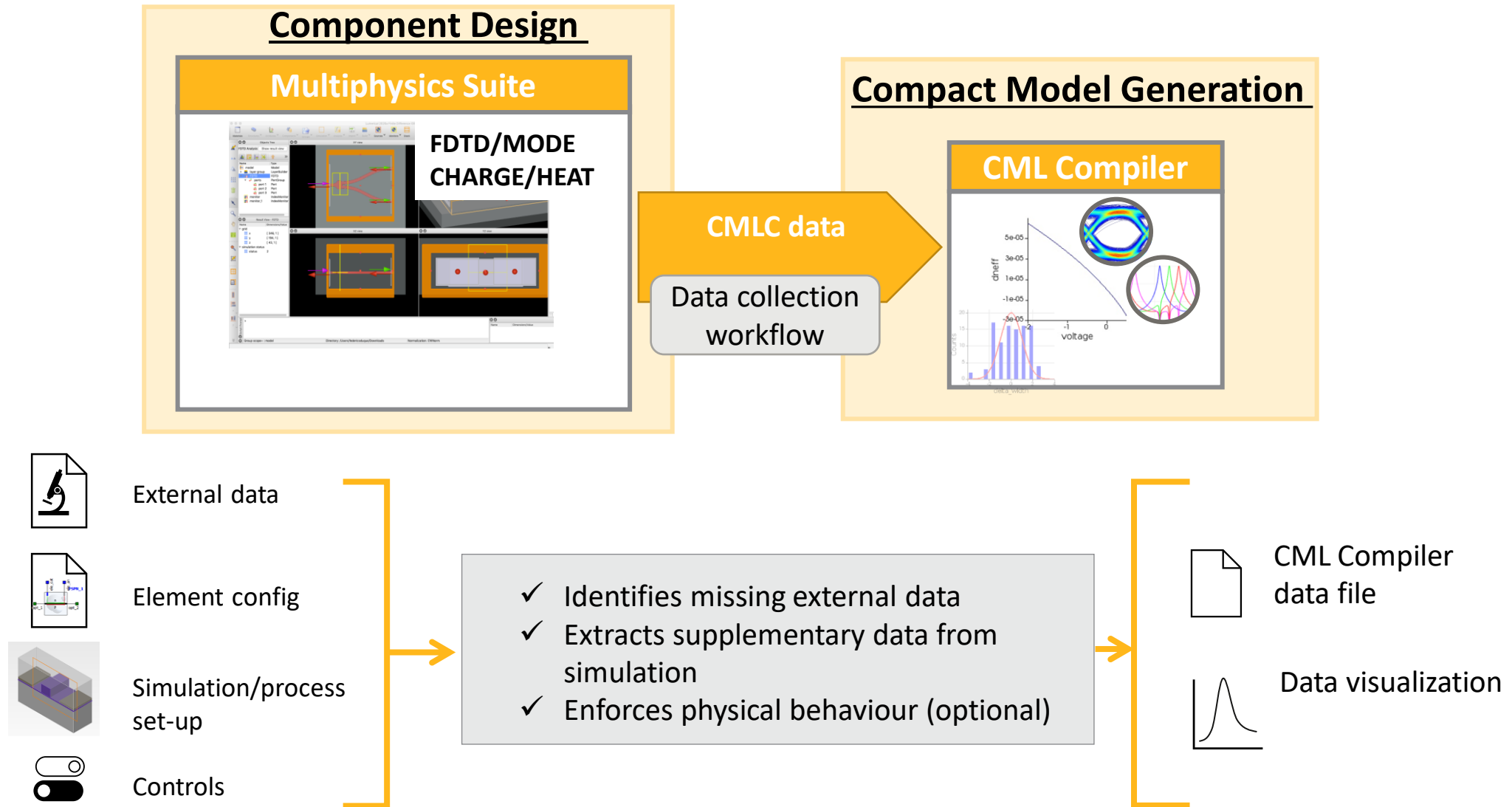
3D geometry



Simulation results



# Automated Data Collection Workflows



<https://support.lumerical.com/hc/en-us/articles/360059773793-Automated-data-collection-workflows>



# / Foundry Process Files Currently Available



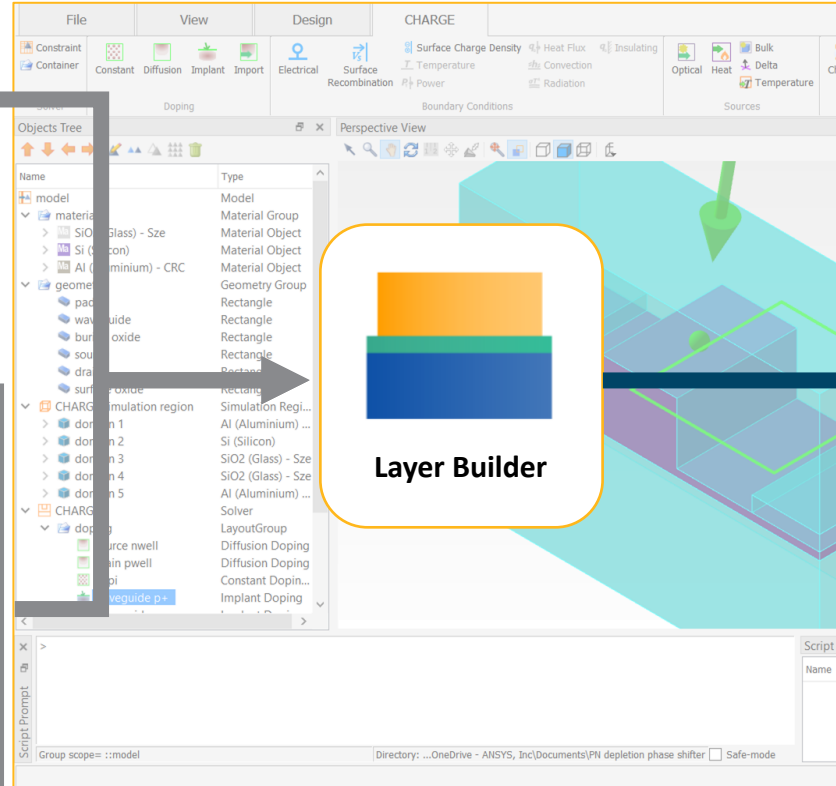
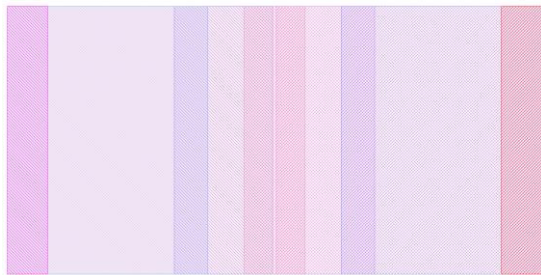
More to come...

# Support for Active Devices

Process file with  
layer definition and  
doping information



GDS-II file with geometry  
and doping patterns

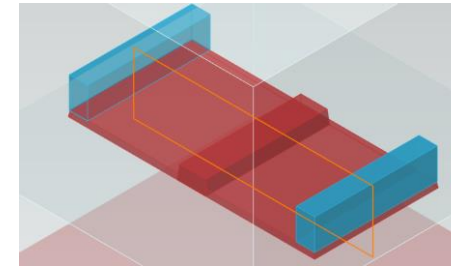


Layer Builder

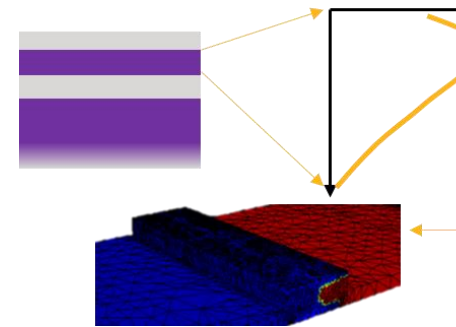
Optical/electrical/  
thermal materials

model	Model
materials	Material Group
Si (Silicon)	Material Object
Si (Silicon)	Semiconductor
Si (Silicon)	Solid
SiO2 (Glass) - Size	Material Object
SiO2 (Glass) - Size	Insulator
SiO2 (Glass) - Size	Solid

3D geometry

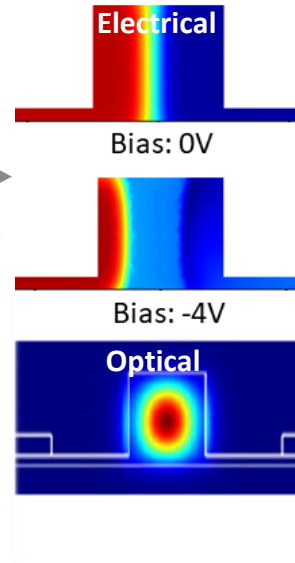


Doping



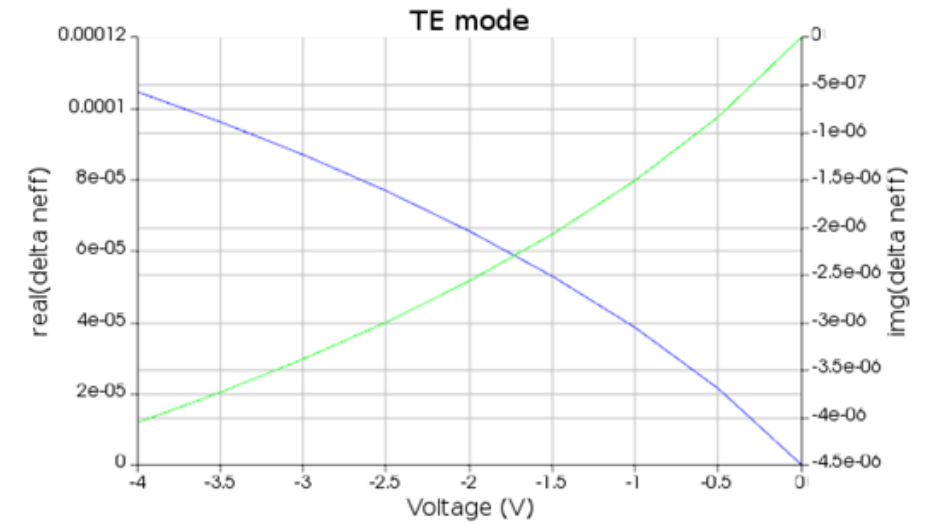
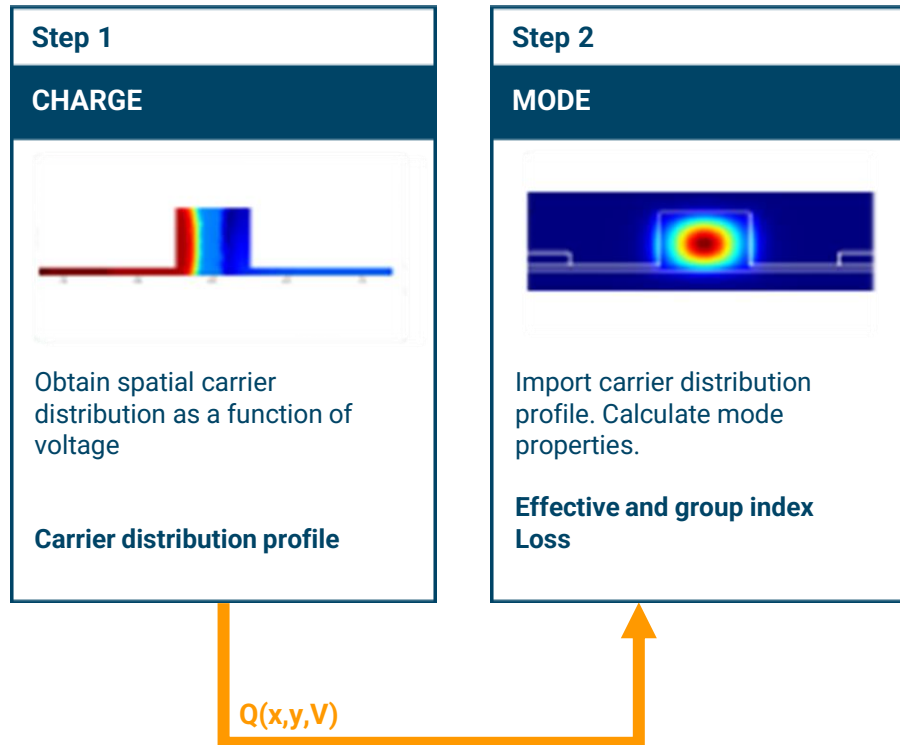
Simulation  
settings

Simulation results

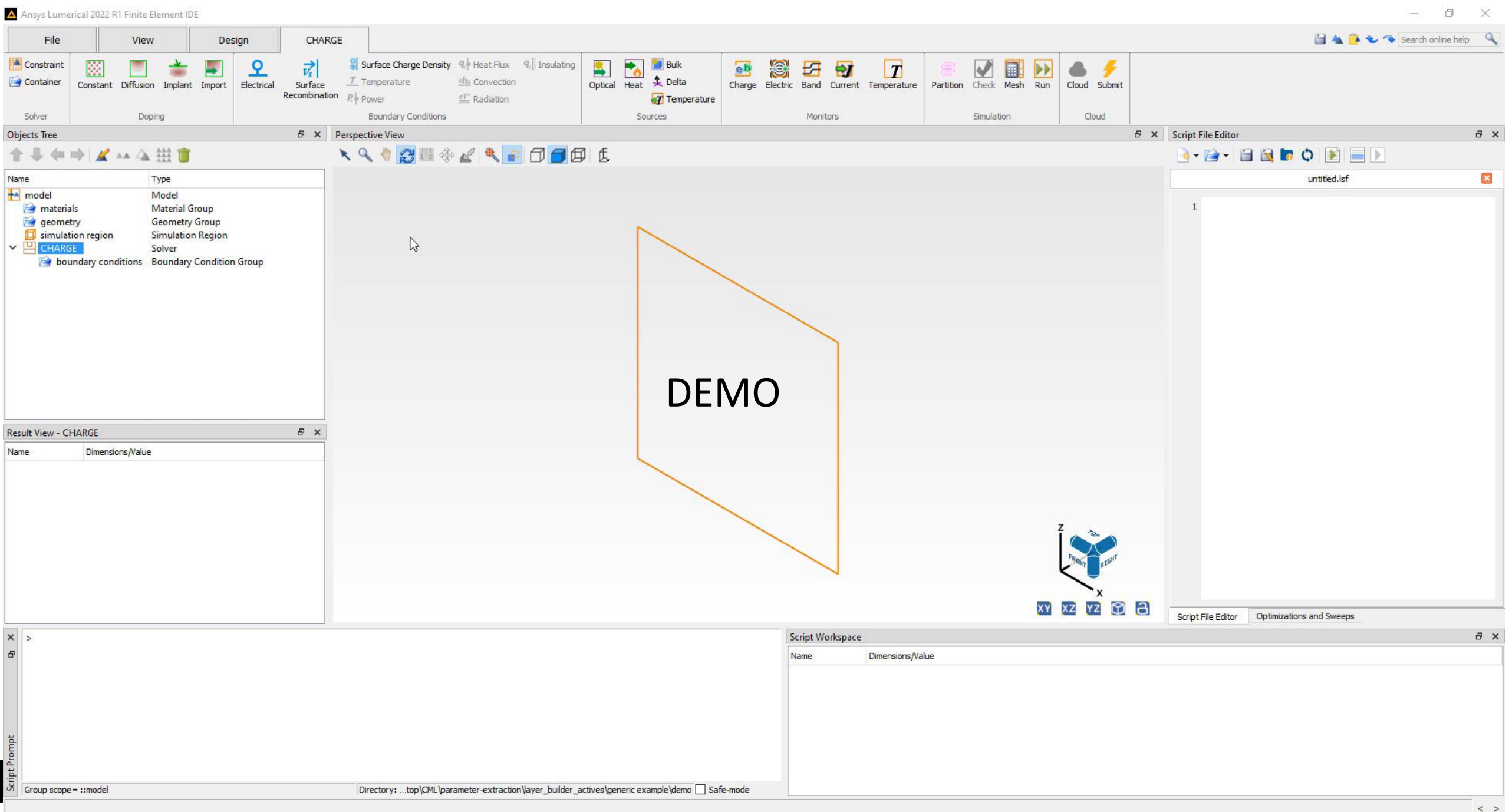


# / Let's See It in Action!

## Simulation workflow of an Electrical Phase Shifter



<https://support.lumerical.com/hc/en-us/articles/360042328674-PN-depletion-phase-shifter>



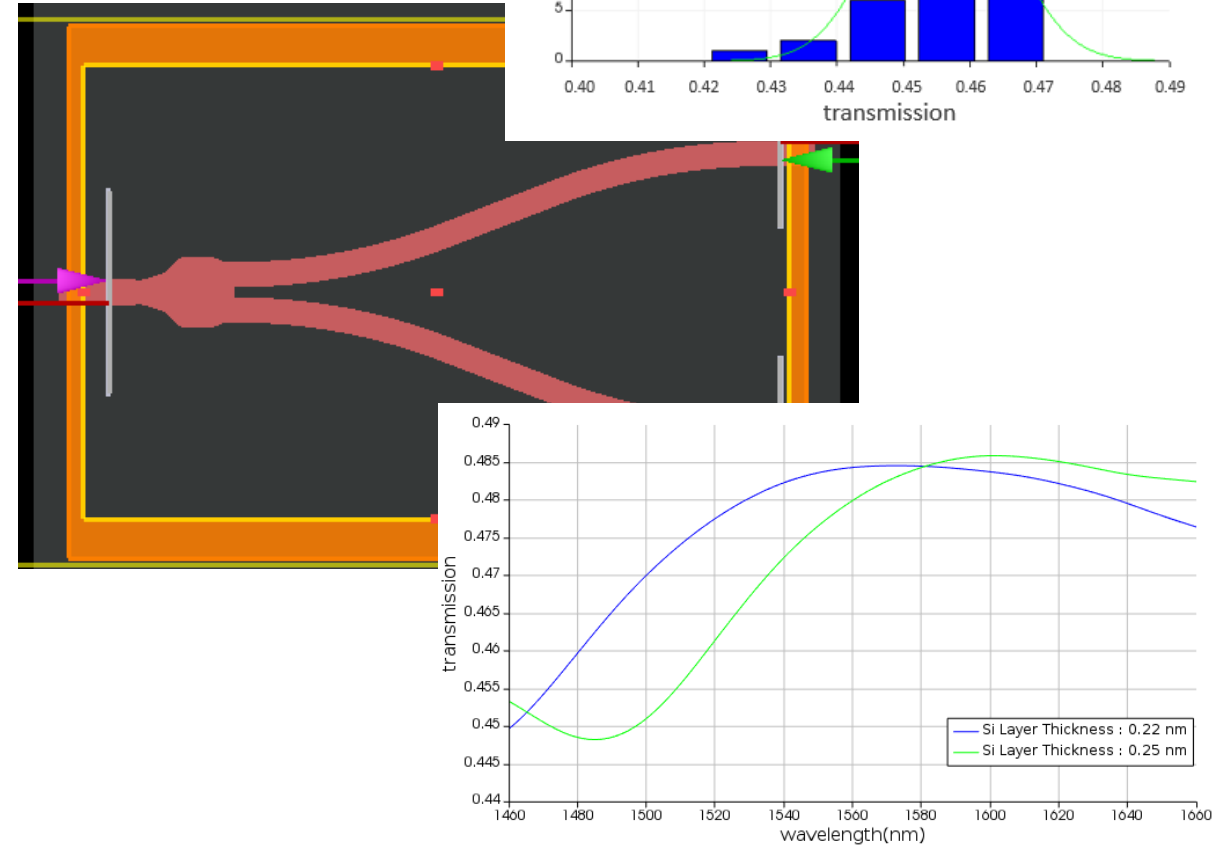
# / Process Variations During Component Design

- Process file to include statistical information:
  - Pattern process parameters: layout bias
  - Stack process parameters: layer thickness, etch depth, etc.
- Statistical simulation methods:
  - Monte Carlo:
    - Statistical variables are randomly varied for a defined number of times and FOMs are studied
    - Most complete, but more expensive
  - Corners:
    - Worst case values of statistical variables are used and FOMs are studied
    - Multiple corner cases can exist

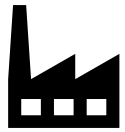


# Example: Process Variation for Y-branch

- SOI layer thickness as a process variable.
- The process variable can be changed randomly and extract transmission results: **Monte Carlo analysis.**
  - Statistical distribution of process variations are required. (for normal distribution: sigma and mean)
- The worst case scenario for the physical process variable can be determined and extract transmission results: **Corner analysis.**
  - Corner cases should be provided
- Superposition of effects of multiple process variables can be modeled.



# End User Workflow

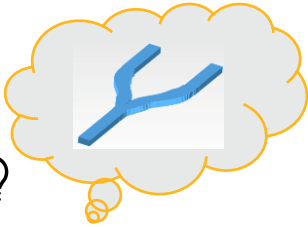


Foundry

Process file including  
process variations

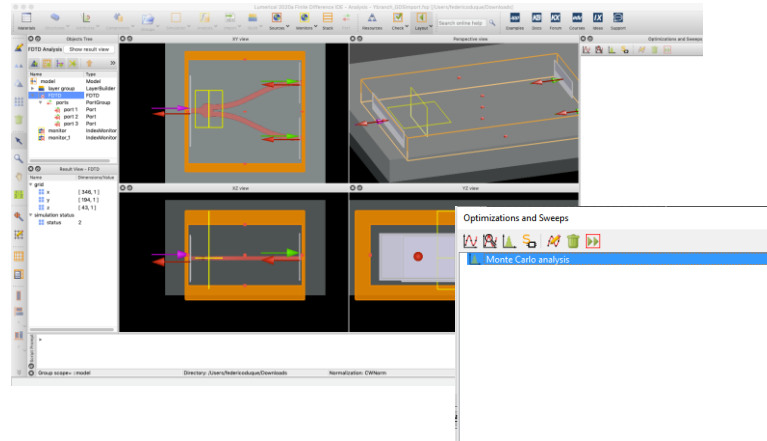


ANSYS / LUMERICAL

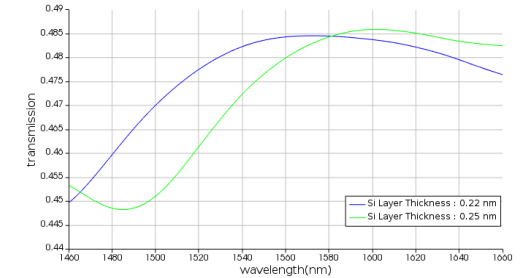


Component designer

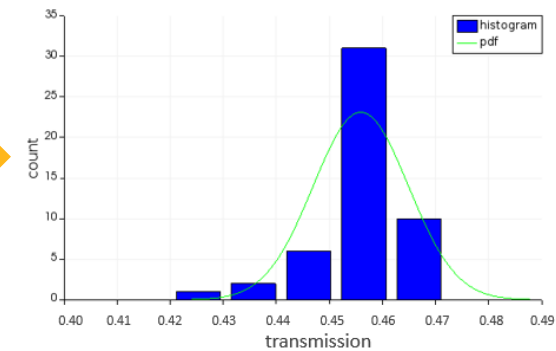
Layer builder



Corner Analysis



Monte Carlo Analysis



# Thank You

## Questions?



 **Ansys**

